

UC Berkeley

## EE C247B - ME C218 Introduction to MEMS Design Spring 2016

Prof. Clark T.-C. Nguyen

Dept. of Electrical Engineering & Computer Sciences  
 University of California at Berkeley  
 Berkeley, CA 94720

Lecture Module 2: Benefits of Scaling

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 1

UC Berkeley

### Physics Package Power Diss. < 10 mW

- Achieved via MEMS-based thermal isolation

Only ~5 mW heating power needed to achieve 80°C cell temperature

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 2

UC Berkeley

### Micro-Scale Oven-Control Advantages

**Macro-Scale**

Macro-Oven (containing heater and T sensor)

Atomic Cell @ 80°C

Insulation

Laser

Thermally Isolating Feet

$R_{th} = 56 \text{ K/W}$   
 $C_{th} = 26 \text{ J/K}$

$P (@ 80^\circ\text{C}) = 1 \text{ W}$

Warm Up,  $\tau = 24 \text{ min.}$

**Micro-Scale**

300x300x300  $\mu\text{m}^3$  Atomic Cell @ 80°C

Heater

Laser

T Sensor (underneath)

Long, Thin Polysilicon Tethers

$R_{th} = 83,000 \text{ K/W}$   
 $C_{th} = 6.3 \times 10^{-6} \text{ J/K}$

$P (@ 80^\circ\text{C}) = 2.6 \text{ mW}$

Warm Up,  $\tau = 0.1 \text{ s}$

$T = P \times R_{th}$

$R_{th} \sim \frac{\text{support length}}{\text{X-section area}}$

$C_{th} \sim \text{volume}$

**308x lower power**

**18,000x faster warm up**

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 3

UC Berkeley

## Micro Gas Analyzers (MGA)

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 4

### Micro Gas Analyzers

**Objective:** enable remote detection of chemical agents via tiny, ultra-low power, fast, chip-scale gas analyzers that greatly reduce the incidence of false positives

**Approach:** use micromachining technologies to implement separation-based analyzers (e.g., gas chromatographs, mass spectrometers) at the micro-scale to enhance gas selectivity

**Conventional Sensor**

**Problem:** polymer has finite sensitivity to both A & B

**Separation Analyzer**

**Result:** species A & B now separated  $\Rightarrow$  can identify and analyze individually

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 5

### Basic Approach: Separation Analyzer

**Tiny Dimensions**

- fast time constants
- 10,000X gain factor via multi-staging
- enhanced sensitivity
- lower power

**Tiny Dimensions**

- faster separation
- lower power

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 7

### Advantages of Miniaturization

**Portable Gas Chromatograph**

**Chip-Scale Gas Chromatograph**

**Reduction Factors**

Size	40,500 cm <sup>3</sup>	<b>20,000X</b>	Size	2 cm <sup>3</sup>
Sensitivity	1 ppb	<b>1,000X</b>	Sensitivity	1 ppt
Analysis Time	15 min.	<b>225X</b>	Analysis Time	4 sec
Energy Per Analysis	10,000 J	<b>10,000X</b>	Energy Per Analysis	1 J

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 6

### Scaling Leads to Faster Separation

**Example:** gas chromatograph separation column

- unique analyte interactions with the column walls
- different analyte velocities
- result:** separation after a finite distance

**Wide Channel:** Carrier Gas (Mobile Phase) interacts with Stationary Phase, leading to Peak Broadens.

**Thin Channel:** Peak Stays Thin  $\Rightarrow$  Less Separation Needed to Resolve.

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 8

### Scaling Leads to Faster Separation

**Example:** gas chromatograph separation column

- unique analyte interactions with the column walls
- different analyte velocities
- result:** separation after a finite distance

240 μm  
150 μm

Wide Channel → Stationary Phase → Miniaturize → Thin Channel

Carrier Gas (Mobile Phase)

Column Width ↓ → Surface-to-Volume Ratio ↑ → Peak Spreading ↓ → Separation Distance ↓

**Result of Scaling:** shorter column length; faster analysis time

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 9

### Basic Approach: Separation Analyzer

Three Analytes → Input Gas Mixture → Pre-Concentrator → Separated Analytes → Separator → Detector → Electronic Processor

Miniaturization

**Tiny Dimensions**

- fast time constants
- 10,000X gain factor via multi-staging
- enhanced sensitivity
- lower power

**Tiny Dimensions**

- faster separation
- lower power

**Tiny Dimensions**

- higher sensitivity
- faster refresh rate
- lower power
- arrays for specificity

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 12

### Gas Chromatography in Less Than 4s!

**Design/Measurement Data:**

- 0.75m x 100μ column
- 0.1μ DB-5 stationary phase
- Heart-cut 275 msec peak injection
- Temperature: ~30 deg C/sec
- H<sub>2</sub> carrier: 35-39 psi at 1 psi/sec

Sandia's micro-GC Column

Green = Analyte  
Blue = Interferent

Peak capacity >40, in 4 sec

Relative Intensity

Elution time [s]

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 12

### Zeptogram Mass Sensors

Nanomechanical Resonator

Shutter

Au

Nozzle

Nanomechanical Resonator

Measurement noise level indicates ~7 zg of resolution

100 zg Au atom clumps resolved!

Frequency Shift (Hz)

Time (sec)

Frequency Shift (Hz)


Mass (zeptograms)

▲ 133 MHz  
■ 190 MHz


>1Hz/zg

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 12


### Gas Analyzer Technology Progression



**Agilent 6852A**  
 Vol: 60,000 cm<sup>3</sup>  
 Power: 20 W  
 Energy/Analysis: 18 kJ  
 Analysis Time: 15 min.



**LLNL**  
 Vol: 40,500 cm<sup>3</sup>  
 Power: 11.5 W  
 Energy/Analysis: 10 kJ  
 Analysis Time: 15 min.



**Sandia uChem Lab**  
 Vol: 1,050 cm<sup>3</sup>  
 Power: 4.5 W  
 Energy/Analysis: 540 J  
 Analysis Time: 2 min.

Gas Chromatograph/Mass Spectrometer (GC/MS) is a "gold standard" in chemical gas detection with excellent immunity to false alarms

**Problems:** too big, too slow, power hungry

**Solution:** use MEMS technology to miniaturize the GC/MS, which in turn makes it faster and more energy efficient

**MGA Objective**  
 Vol: 2 cm<sup>3</sup>  
 Power: <200 mW  
 Energy/Analysis: 1 J  
 Analysis Time: 4 s

➔ small enough for projectile delivery  
➔ 1 ppt det. limit  
➔ very fast  
➔ battery operable

### Messages Going Forward ...

- MEMS are micro-scale or smaller devices/systems that operate mainly via a mechanical or electromechanical means
- MEMS ⇒ NEMS offer the same scaling advantages that IC technology offers (e.g., speed, low power, complexity, cost), but they do so for domains beyond electronics:

Size ↓ ➔

resonant frequency ↑ (faster speed)

actuation force ↓ (lower power)

# mechanical elements ↑ (higher complexity)

integration level ↑ (lower cost)

- Micro ... nano ... *it's all good*
- Just as important: MEMS or NEMS have brought together people from diverse disciplines ⇒ this is the key to growth!
- What's next? ⇒ Nano-nuclear fusion? Chip-scale atomic sensors?

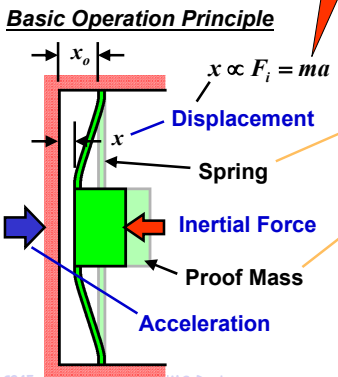
... limitless possibilities ...

### Example: Micromechanical Accelerometer

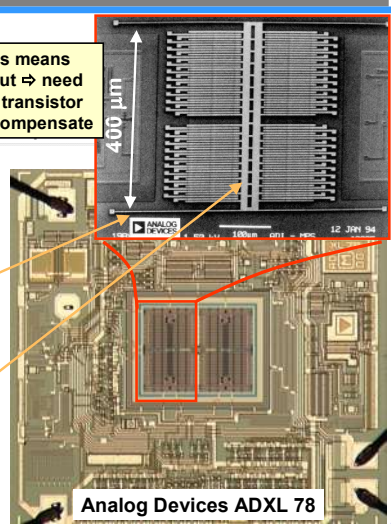
**The MEMS Advantage:**

- ↳ >30X size reduction
- ↳ accelerometer mech
- ↳ allows integration

**Basic Operation Principle**



Tiny mass means small output ⇒ need integrated transistor circuits to compensate



Analog Devices ADXL 78